SUPPORTING INFORMATION FOR:

Two-Photon Lithography in Visible and NIR Ranges Using Multibranched-based Sensitizers For Efficient Acid Generation

Ming Jin*[a], Jianchao Xie [a], Jean-Pierre Malval*[b], Arnaud Spangenberg[b], Olivier Soppera [b], Davy-Louis Versace [c], Tiffanie Leclerc [b], Haiyan Pan [a], Decheng Wan [a], Hongting Pu[a], Patrice Baldeck [d], Olivier Poizat[e] and Stephan Knopf [b]

[a] School of Materials Science and Engineering, Tongji University, Shanghai 201804, P.R. China.
[b] Institut de Science des Matériaux de Mulhouse, UMR CNRS 7361, Université de Haute-Alsace, 15 rue Jean Starcky, 68057 Mulhouse, France.
[c] Institut de Chimie et des Matériaux Paris-Est, UMR 7182, 2-8 rue Henri Dunant, 94320 Thiais. Université Paris-Est Créteil Val de Marne, France.
[d] Laboratoire de Spectrométrie Physique, UMR CNRS 5588. Université Joseph Fourier, 38402 Saint Martin d'Hères, France.
[e] Laboratoire de Spectrochimie Infrarouge et Raman, UMR CNRS 8516. Université des Sciences et Technologies de Lille. 59655 Villeneuve d'Ascq Cedex

Contact: mingjin@tongji.edu.cn or jean-pierre.malval@uha.fr

CONTENTS

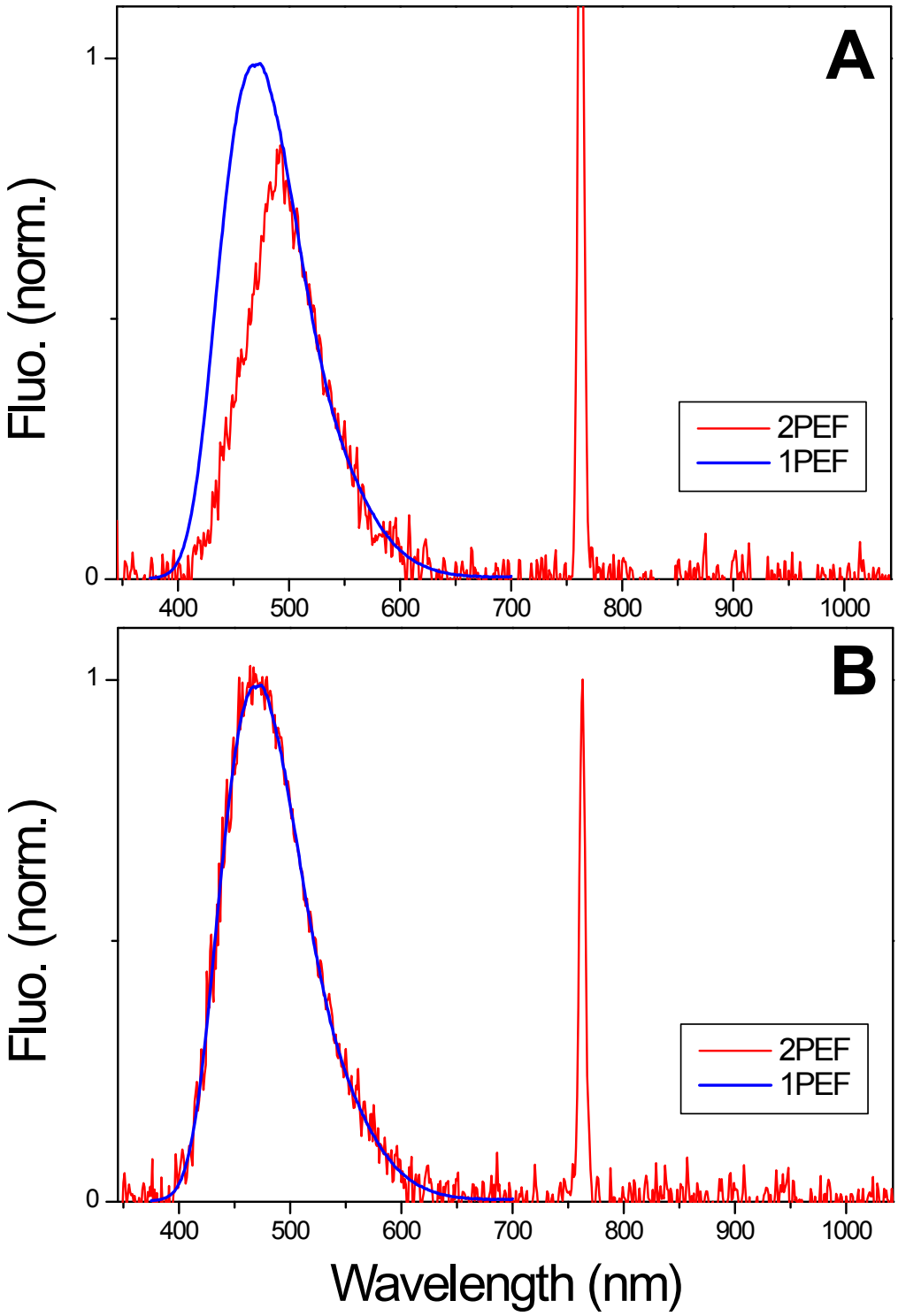
A
B
Fluo. (norm.)
Fluo. (norm.)
1
0
1
0
2PEF
1PEF
2PEF
1PEF
400
500
600
700
800
900
1000
400
500
600
700
800
900
1000
Wavelength (nm)

Figure S1.

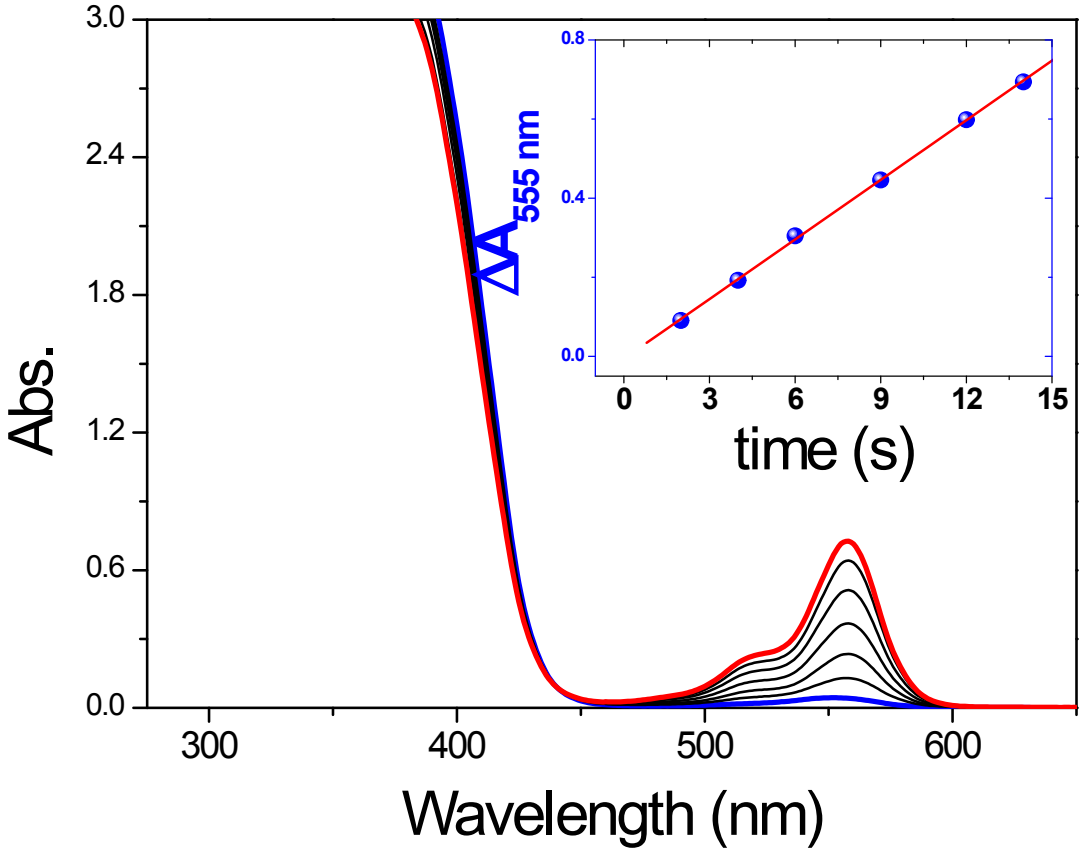
Abs.
Wavelength (nm)
3.0
2.4
1.8
1.2
0.6
0.0
300
400
500
600
ΔA555 nm
0.8
0.4
0.0
0
3
6
9
12
15
time (s)

Figure S2.

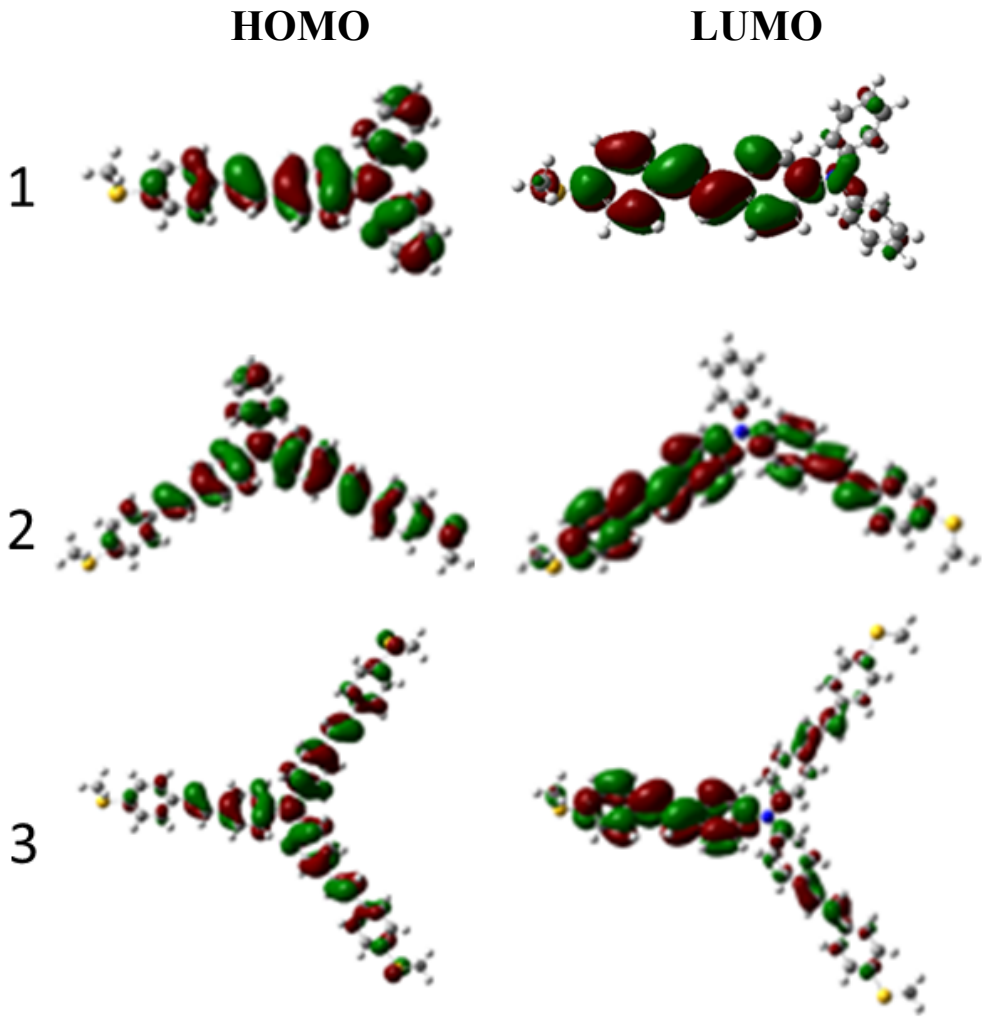

Figure S3.

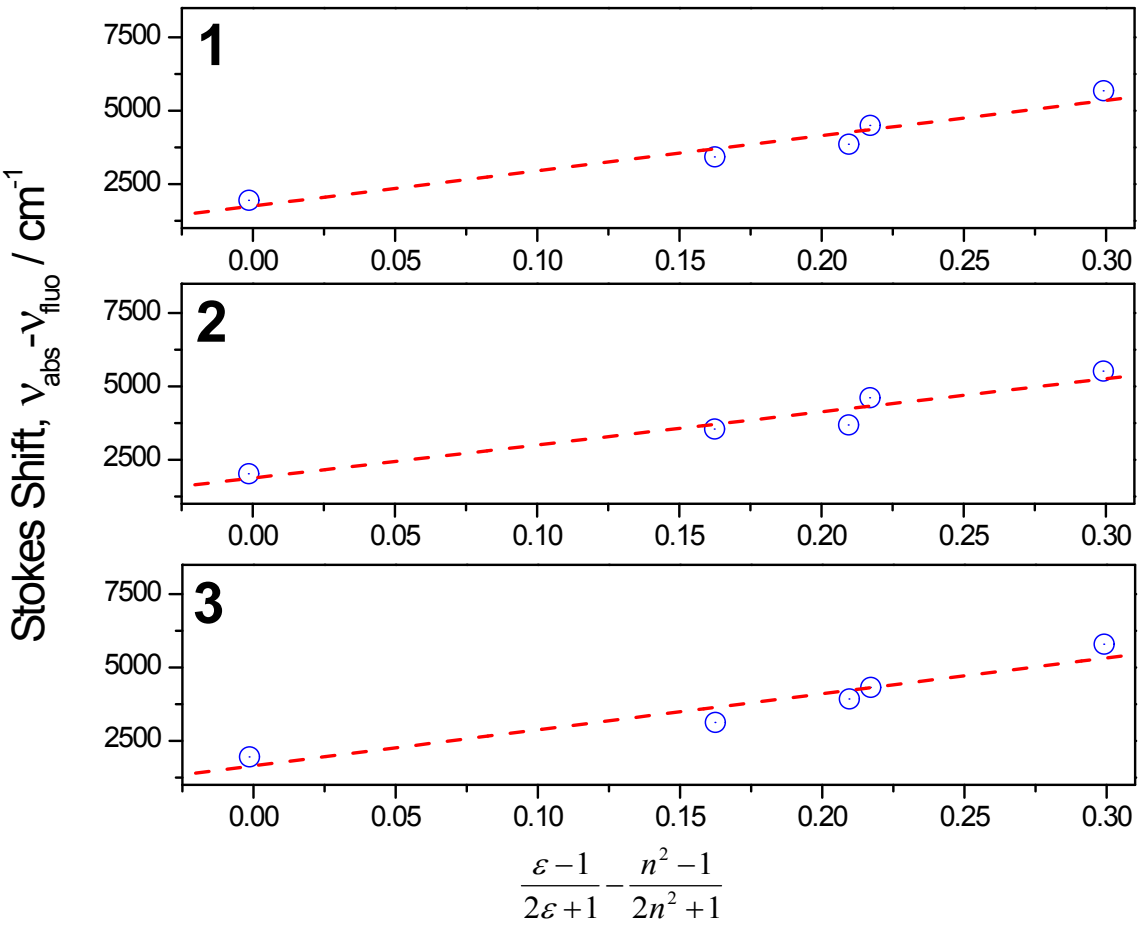
1
2
3
7500
5000
2500
0.00
0.05
0.10
0.15
0.20
0.25
0.30
Stokes Shift, ν_{abs}-ν_{fluo} / cm^{-1}
$\frac{\varepsilon-1}{2\varepsilon+1}-\frac{n^2-1}{2n^2+1}$

Figure S4.

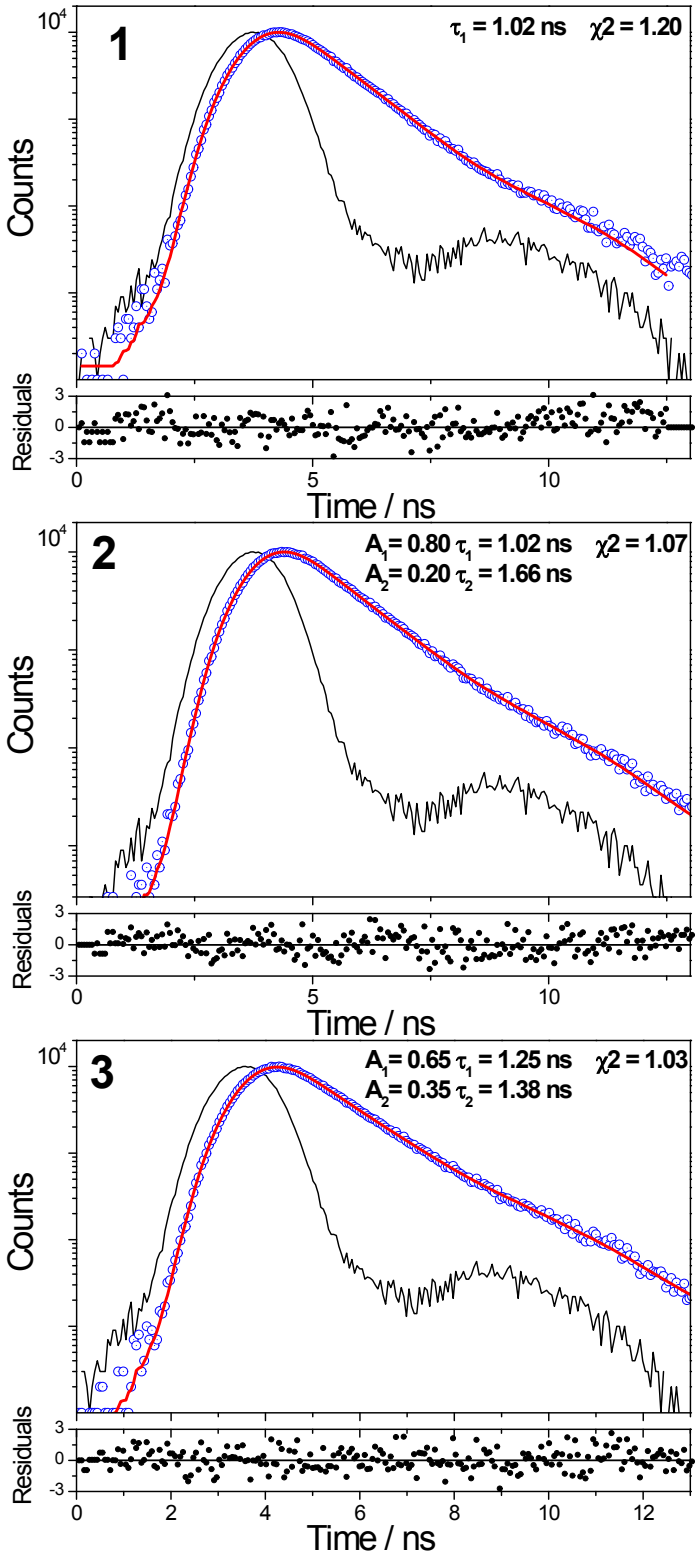
1
τ1 = 1.02 ns χ2 = 1.20
Counts
Residuals
Time / ns
2
A1 = 0.80 τ1 = 1.02 ns χ2 = 1.07
A2 = 0.20 τ2 = 1.66 ns
Counts
Residuals
Time / ns
3
A1 = 0.65 τ1 = 1.25 ns χ2 = 1.03
A2 = 0.35 τ2 = 1.38 ns
Counts
Residuals
Time / ns

Figure S5.

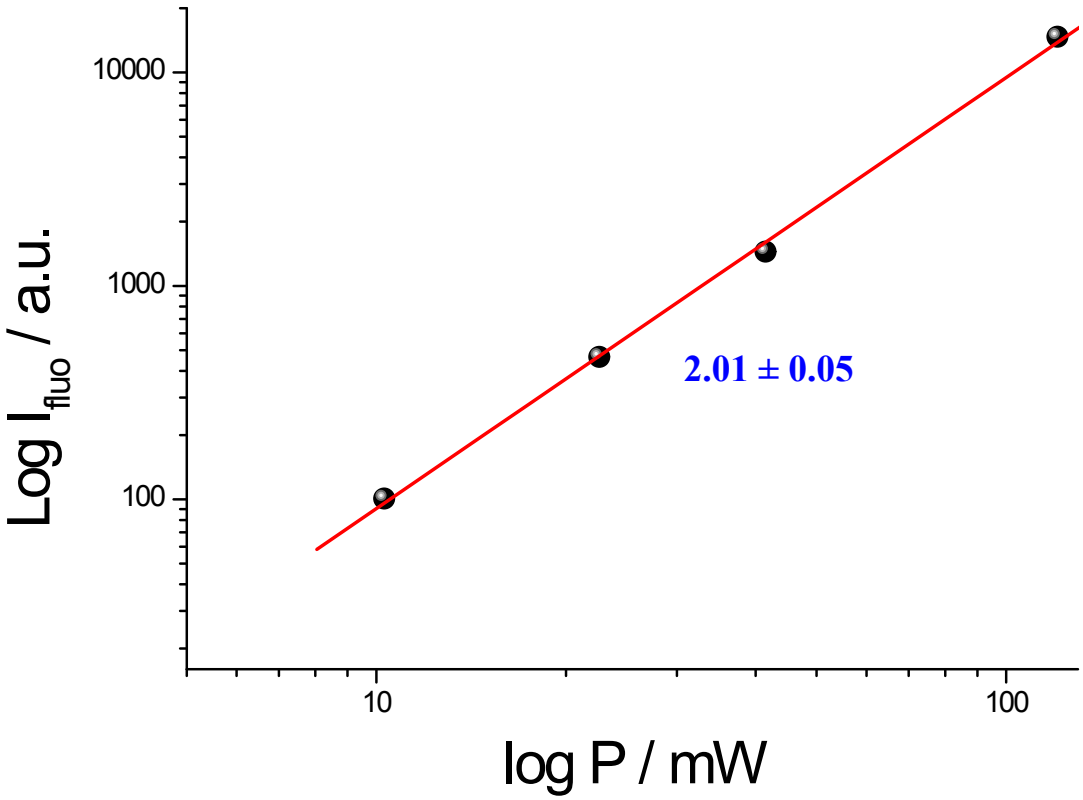

Figure S6.

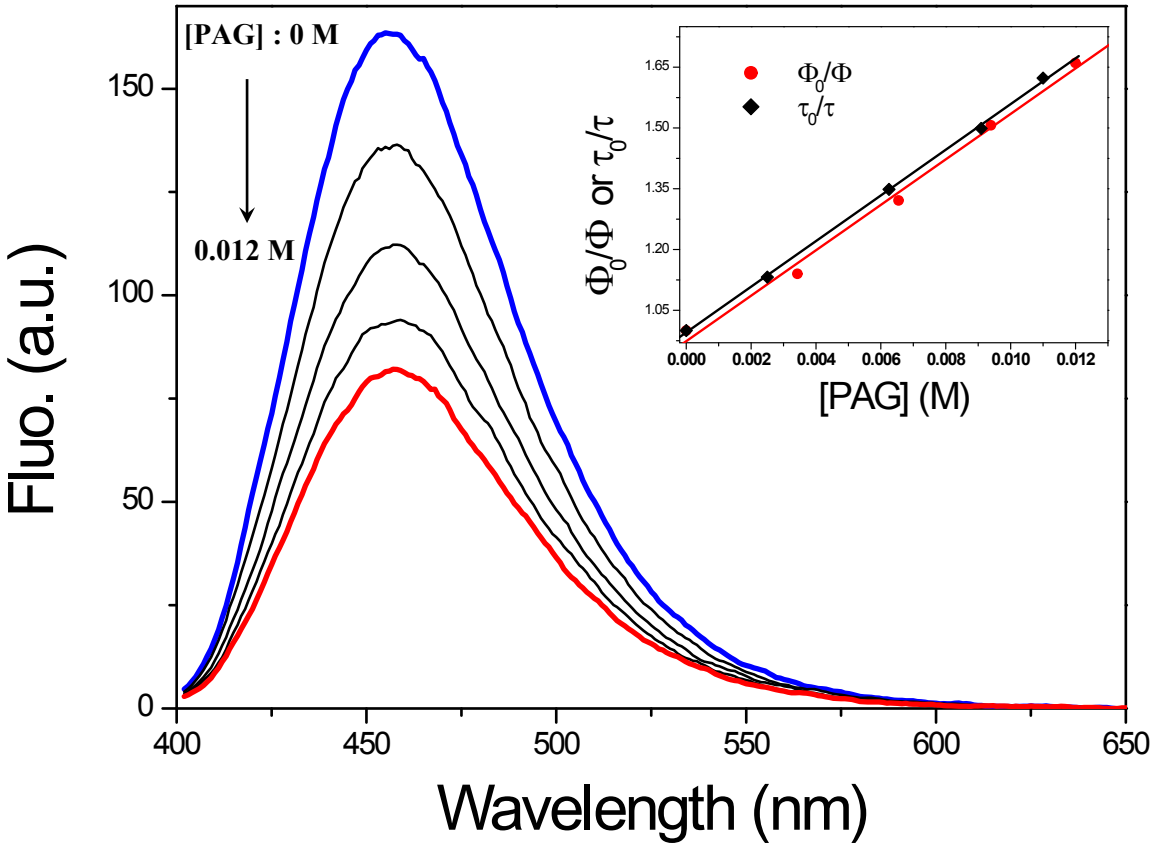
[PAG] : 0 M
0.012 M
Fluo. (a.u.)
Wavelength (nm)
0
50
100
150
400
450
500
550
600
650
Φ0/Φ
τ0/τ
Φ0/Φ or τ0/τ
[PAG] (M)
1.05
1.20
1.35
1.50
1.65
0.000
0.002
0.004
0.006
0.008
0.010
0.012

Figure S7.

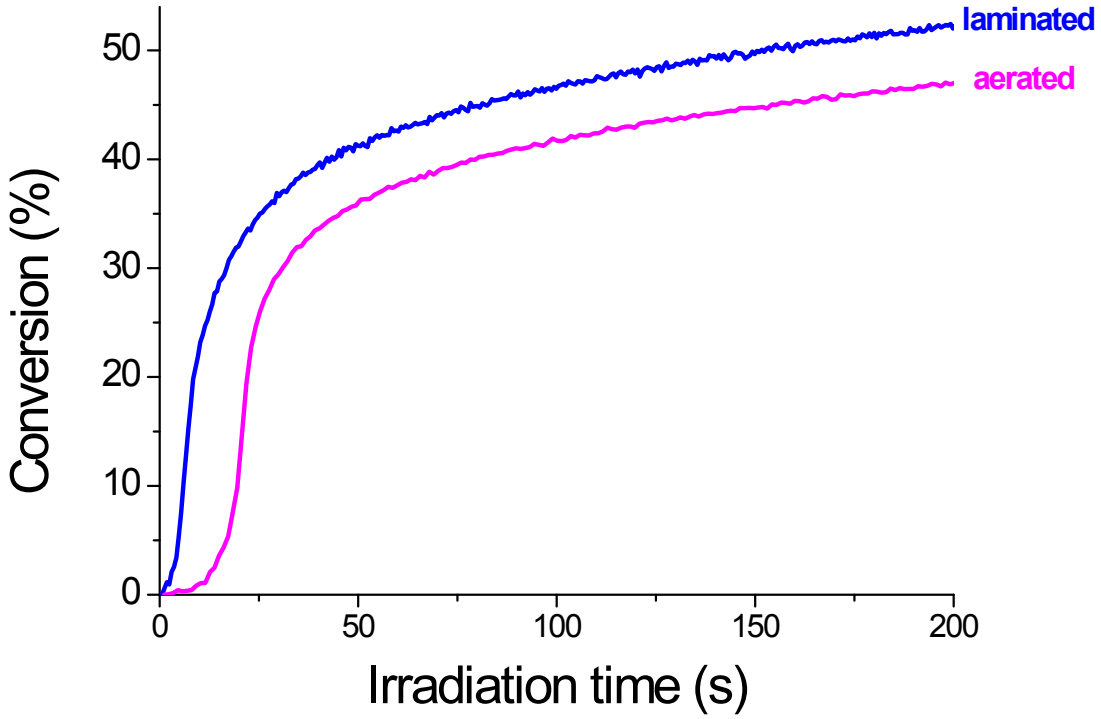
laminated
aerated
Conversion (%)
Irradiation time (s)
0
10
20
30
40
50
0
50
100
150
200

Figure S8.